

L Number	Hits	Search Text	DB	Time stamp
1	831	269/55.cccls. or 269/56.cccls. or 269/57.cccls.	USPAT	2003/12/12 16:26
-	65	((article and (station or stations)) and ((MEMS adj die) or (MEMS) or (die))) and apparatus and (tool or arm)) and (teflon)	USPAT	2003/08/22 18:33
-	13	MEMS adj die	USPAT	2002/11/26 23:34
-	288	438/\$.cccls. and MEMS	USPAT	2002/11/26 23:35
-	351	438/\$.cccls. and (MEMS or (microelectromechanical))	USPAT	2002/11/27 00:54
-	94	29/603.17 or 29/603.19	USPAT	2002/11/26 23:53
-	59	29/603.17.cccls. or 29/603.19.cccls.	USPAT	2002/11/26 23:53
-	39	29/650.cccls.	USPAT	2002/11/26 23:55
-	824	269/55.cccls. or 269/56.cccls. or 269/57.cccls.	USPAT	2003/12/12 16:26
-	3	269/\$.cccls. and mems	USPAT	2002/11/27 00:25
-	3	269/\$.cccls. and (micromechanical)	USPAT	2002/11/27 00:26
-	562	269/\$.cccls. and semiconductor	USPAT	2002/11/27 00:44
-	131	257/\$.cccls. and MEMS	USPAT	2002/11/27 00:58
-	705	438/455.cccls. or 438/456.cccls. or 438/458.cccls.	USPAT	2002/11/27 01:08
-	27	(438/455.cccls. or 438/456.cccls. or 438/458.cccls.) and teflon	USPAT	2002/11/27 01:09
-	1	(414/935.cccls. or 414/936.cccls. or 414/937.cccls. or 414/938.cccls. or 414/939.cccls. or 414/940.cccls. or 414/941.cccls.) and MEMS	USPAT	2003/05/08 13:17
-	1561	414/935.cccls. or 414/936.cccls. or 414/937.cccls. or 414/938.cccls. or 414/939.cccls. or 414/940.cccls. or 414/941.cccls.	USPAT	2003/12/12 14:14
-	0	269/\$.cccls. and (MEMS adj die)	USPAT	2003/05/08 13:23
-	578	269/\$.cccls. and (semiconductor)	USPAT	2003/05/08 13:21
-	0	269/\$.cccls. and (micro adj electro adj mechanical adj die)	USPAT	2003/05/08 13:21
-	1	269/\$.cccls. and (micro adj electro adj mechanical)	USPAT	2003/05/08 13:23
-	0	(414/935.cccls. or 414/936.cccls. or 414/937.cccls. or 414/938.cccls. or 414/939.cccls. or 414/940.cccls. or 414/941.cccls.) and (MEMS adj die)	USPAT	2003/05/08 13:23
-	1	(414/935.cccls. or 414/936.cccls. or 414/937.cccls. or 414/938.cccls. or 414/939.cccls. or 414/940.cccls. or 414/941.cccls.) and (MEMS)	USPAT	2003/05/08 13:23
-	0	(414/935.cccls. or 414/936.cccls. or 414/937.cccls. or 414/938.cccls. or 414/939.cccls. or 414/940.cccls. or 414/941.cccls.) and (micro adj electro adj mechanical)	USPAT	2003/05/08 13:23
-	0	(414/935.cccls. or 414/936.cccls. or 414/937.cccls. or 414/938.cccls. or 414/939.cccls. or 414/940.cccls. or 414/941.cccls.) and (microelectromechanical-systems)	USPAT	2003/05/08 13:23
-	258	(414/935.cccls. or 414/936.cccls. or 414/937.cccls. or 414/938.cccls. or 414/939.cccls. or 414/940.cccls. or 414/941.cccls.) and flexible	USPAT	2003/05/08 13:26
-	34	(414/935.cccls. or 414/936.cccls. or 414/937.cccls. or 414/938.cccls. or 414/939.cccls. or 414/940.cccls. or 414/941.cccls.) and (flexible with arm)	USPAT	2003/05/08 13:26
-	369	269/55.cccls.	USPAT	2003/08/22 18:16
-	0	station and recess and (flexible adj reatining adj arm)	USPAT	2003/08/22 18:17
-	0	flexible adj reatining adj arm	USPAT	2003/08/22 18:17
-	27	flexible adj retaining adj arm	USPAT	2003/08/22 18:31
-	136	((269/\$.cccls. and (station or stations)) and recess) and arm	USPAT	2003/08/25 00:46
-	104	(269/\$.cccls. and (station or stations)) and ((station or stations) with (wheel or wheels or disc or discs or circle or circles or round or circular or spin))	USPAT	2003/08/25 00:22
-	15	269/\$.cccls. and (flexible adj arm)	USPAT	2003/08/25 00:45
-	4	269/\$.cccls. and (fluoropolymer)	USPAT	2003/08/25 00:46
-	181	269/\$.cccls. and teflon	USPAT	2003/08/25 00:46
-	3	((269/\$.cccls. and (station or stations)) and recess) and arm and teflon	USPAT	2003/08/25 00:55
-	23	269/\$.cccls. and ((retaining adj arm) or (retain adj arm) or (retainer adj arm))	USPAT	2003/08/25 00:59
-	24	((retaining adj arm) or (retain adj arm) or (retainer adj arm)) and (wafer)	USPAT	2003/08/25 00:59
-	3551	((microelectromechanical adj systems) or MEMS)	USPAT	2003/12/12 14:19
-	8	(((microelectromechanical adj systems) or MEMS)) and fluoropolymer	USPAT	2003/12/12 14:16

-	2850	((microelectromechanical adj systems) or MEMS)) and (recess or structural or station or slot or carrier or machine or article or apparatus)	USPAT	2003/12/12 14:17
-	2208	((microelectromechanical adj systems) or MEMS)) and (tool or machine or article or apparatus)	USPAT	2003/12/12 14:18
-	809	((microelectromechanical adj systems) or MEMS)) and (29/\$.ccls. or 269/\$.ccls. or 257/\$.ccls. or 438/\$.ccls. or 414/\$.ccls.)	USPAT	2003/12/12 14:21
-	217	((((microelectromechanical adj systems) or MEMS)) and (29/\$.ccls. or 269/\$.ccls. or 257/\$.ccls. or 438/\$.ccls. or 414/\$.ccls.)) and (tool or machine)	USPAT	2003/12/12 14:21